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Major US Computer Chip Manufacturer Orders Dainippon Screen's Wet Station

Dainippon Screen Mfg. Co., Ltd. ("Screen", headquarters: Kyoto, Japan; president: Akira Ishida) has received a sizable capital equipment order for their advanced state-of-the-art 300mm cleaning system, the FC-3000 Wet Station, from a major U.S. based chip manufacturer, promoting for a "300mm Project". The order represents another major win for Screen's 300mm cleaning equipment. The products are scheduled to be delivered at the end of this year.

The FC-3000 includes many features that distinguish it as an advanced tool for the 300mm market. This state of the art wafer cleaning systems uses a hybrid technology of chemical circulation and chemical replacement as part of the single-bath cleaning capability on the process tool. The FC-3000's ability to perform a series of cleaning processes in a single bath results in higher levels of cleanliness, while providing a wide range of flexible cleaning processes. This flexibility enables the system to serve a vast array of cleaning strategies employed throughout the industry including concentrated and dilute chemistry applications. Moreover, the FC-3000 helps lower running costs by reducing the system's size. It is equipped with fast and accurate robotic transfer systems, which enable loading of up to six baths at a time to enhance the overall system throughput. The tool also integrates directly into advanced 300mm fabs being constructed with careful attention paid to such items as factory automation, automated material handling systems, ES&H, process environment integrity, and maintainability. Finally, the FC-3000 carries on Screen's reputation for fielding equipment considered the most reliable in the industry.

New "FC-1"production facility
for FC-3000

300mm wafer cleaning system
"FC-3000"

The first FC-3000 was shipped in the first half of fiscal year 1999. As of April, 2001, 50 units have been supplied in Japan, Taiwan, and the U.S. This recent order represents the third U.S. company to adopt Screen's cleaning equipment for 300mm wafers. Although capital investment in the semiconductor manufacturing industry has been in decline recently, investment for 300mm wafer equipment is progressing as expected. FC-3000's are manufactured at Screen's new FC-1 production facility which was opened in March 2001 to exclusively manufacture 300mm cleaning systems. The Company is forecasting shipment of 100 FC-3000's this fiscal year.

<Product Information>

Takayuki Hanafusa (Mr.)
Dainippon Screen Mfg. Co., Ltd
Semiconductor Equipment Division, Business Planning Dep.
Teranouchi-agaru 4, Horikawa-dori, Kamigyo-ku, Kyoto, 602-8585, Japan
Phone: +81-75-417-2527, Fax: +81-75-417-2546, E-mail: hanafusa@screen.co.jp